Docket No.: OGOSH46USA

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/567,729 Confirmation No. 7682

Applicant : Kazutoshi Kojima et al.

371 Filed : February 1, 2006

Art Unit : 2814

Examiner : Sarah Kate Salerno

Customer No. : 00270

Title : SILICON CARBIDE EPITAXIAL WAFER, METHOD FOR

PRODUCING SUCH WAFER, AND SEMICONDUCTOR

DEVICE FORMED ON SUCH WAFER

Mail Stop Amendment Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT

Sir:

This is an Amendment in timely response to a non-final Office Action dated March 31, 2009. Kindly amend the application as set forth below.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.